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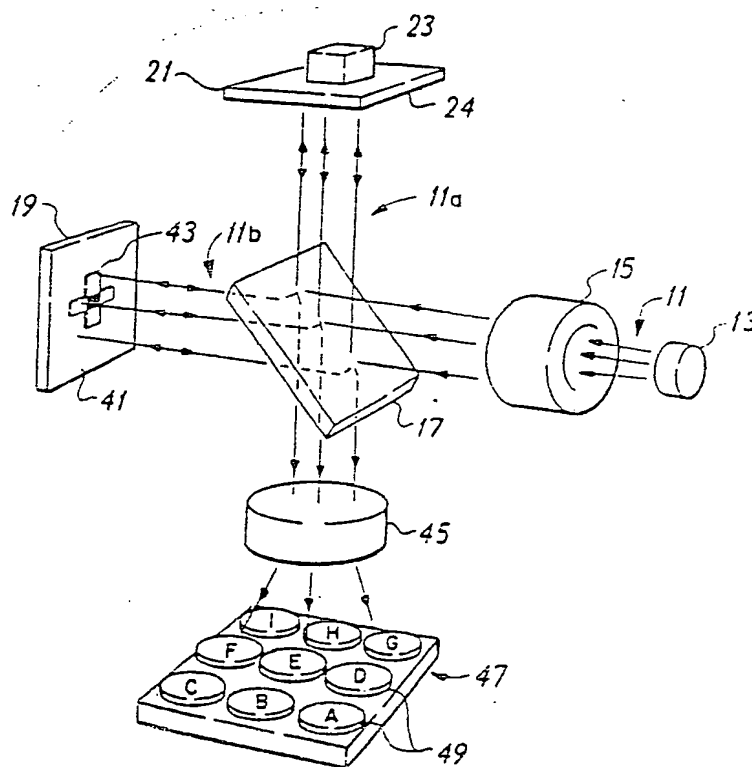
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(54) Title: VIBRATION COMPENSATING INTERFEROMETER MIRROR DRIVE SYSTEM

(57) Abstract

A interferometer mirror drive system compensates for velocity and tilt errors induced by ambient vibration, as well as providing long-term automatic alignment of the mirrors. A uniquely configured $\lambda/8$ -thick step on the fixed mirror of the interferometer introduces a 90-degree phase shift in one of two reference light beams, to produce quadrature signals which characterize the relative between the fixed and the driven mirrors. An electronic circuit extracts velocity and tilt data from the quadrature signals and develops error signals indicative of deviations from the desired coordinates of the moving mirror. The error signals are used to generate a set of control signals which in turn are supplied to an arrangement of drive coils attached to the moving mirror, to restore the mirror to the desired coordinates.



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1 Vibration compensating interferometer mirror drive
system

Background of the Invention

5 The present invention relates in general to the
field of scanning mirror interferometers, and in par-
ticular to a system for correcting vibration-induced
errors in the movement of the scanning mirror.

Fourier Transform Infrared (FTIR) Spectrometers
have achieved a widespread degree of popularity for the
10 spectral analysis of chemical compositions. At the
heart of the FTIR spectrometer is a Michelson Inter-
ferometer in which light from a broadband infrared
source is split into two beams, to be reflected off a
fixed mirror and a moving mirror respectively. The
15 beams are recombined and irradiate an unknown sample,
before impinging on a detector. The intensity of the
recombined beam as a function of moving mirror posi-
tion, which is made up of contributions of different
wavelengths within the infrared source, is known as an
20 interferogram. Performing a Fourier transform on the
interferogram yields a spectrum identifying the infra-
red-absorbing constituents of the sample.

The accuracy of a continuous scan interferometer
spectrometer is closely related to its ability to
25 translate the moving mirror at a constant speed, and
in a direction such that its reflecting surface remains
normal to the light beam incident thereon. When used
in a laboratory environment the instrument generally
can be isolated effectively from external vibrations
30 which otherwise would introduce fluctuations in the
mirror speed and angular position. However, FTIR
spectrometers are being used increasingly as airborne
instrumentation, for example in space research, and



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1 also in on-line situations where they are coupled to a manufacturing process to insure consistent product quality.

5 In these latter two situations, external vibrations are quite common, and so compensating schemes must be included within the spectrometer to negate the effects of the vibrations.

Several techniques have been used in the prior art to provide vibration compensation. One approach has
10 been to sense the deviation in the tilt or the velocity of the moving mirror from predetermined settings by comparison with reference signals, and to compensate for the deviations, using either mechanical or mathematical techniques. In the mechanical compensation
15 mode, error signals derived from the instantaneous moving mirror position are fed back through a servo system to one or more of a variety of mechanisms which readjusts the mirror tilt or velocity. In some cases, the compensation is applied directly to the main drive
20 mechanism of the moving mirror, as shown in U.S. Patent Nos. 3,488,123 and 4,149,118. In other cases auxiliary mechanisms, coupled to either the moving or the fixed mirror apply the necessary corrections, as disclosed in U.S. Patent No. 3,809,481 and in "Fourier Spectro-
25 scopy Applied to Field Measurements," by G. W. Ashley and A. G. Tescher. Special Reports No. 114, Aspen International Conference on Fourier Spectroscopy, Jan. 5, 1971.

30 In the mathematical mode, electronic, or similar, circuitry subtracts the effects of mirror tilt or velocity deviations from the spectral information as it is being processed.

Another common approach is to use a rigid, precise-



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1 ly machined transport mechanism for the moving mirror
which, due to its rigidity, does not permit the mirror
to deviate significantly from its desired path, or from
its desired speed. This approach may entail the use
5 of lead screw or air bearing mechanisms coupled with a
mirror-bearing carriage which rides along a precisely
machined track, the close tolerances between the
carriage and the track substantially eliminating fluctu-
ations in mirror position. Nevertheless, an auxil-
10 iary servo mechanism, coupled with a feedback loop,
usually is needed to adjust for mirror deviations.
Examples of such hybrid systems are shown in U.S.
Patent No. 4,053,231 and in "Interferometer Design and
Data Handling in a High-vibration Environment - Part I
15 Interferometer Design" by R. P. Walker and J. D. Rex,
SPIE Vol. 191 Multiplex and/or High-Throughput Spectro-
scopy (1979).

There have been deficiencies in these prior art
attempts to solve the vibration problem. The precisely
20 machined mirror transport mechanisms are generally
quite expensive to manufacture, and are susceptible to
wear, which erodes the accuracy of the interferometer.
Therefore, continual attention and maintenance are
required. On the other hand, the feedback schemes
25 which correct for deviations from desired mirror tilt
and velocity are often quite complex and expensive, and
are limited as to the range of vibration frequencies
to which they can respond. The deviations in mirror
movement are usually sensed by observing fluctuations
30 in the periodicity of the zero crossings of the inter-
ference fringes. However, since there is not a con-
tinuous observation of mirror position, but only at the
two times per cycle when the interference fringes



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1 experience a zero crossing, the responses of such feed-back schemes have been severely band-width-limited.

Also, a particular compensating mechanism typically corrects for either velocity or tilt, but not for both.
• 5 Therefore multiple schemes are needed to adjust both parameters simultaneously.

Therefore, in light of the foregoing it is an object of the present invention to provide a simplified vibration-compensating mirror drive system which simultaneously controls both mirror tilt and velocity, and
10 does so in a highly reliable, easily maintainable and relatively inexpensive fashion.

It is a further object of the invention to achieve improved bandwidth in a vibration-compensation scheme
15 by a continuous derivation of mirror position and velocity data, so as to compensate for vibrations having a wide range of frequencies.

SUMMARY OF THE INVENTION

An embodiment of the present invention operates in
20 the context of a mirror drive control system for an interferometer used for spectroscopic analysis, in which a first light beam derived from a monochromatic source impinges on a fixed mirror and a second light beam derived from the same monochromatic source im-
25 pinges on a moving mirror. The moving mirror is supposed to be scanned at a constant rate and at a constant angular tilt relative to the direction of the light beam incident on its reflective surface. The first and second light beams are recombined at an
30 optical detector after reflection from the respective mirrors. The embodiment further includes a drive mechanism which both moves the moving mirror and adjusts its angular tilt. There is also an element



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1 for deriving from the detected recombined light beams
both a first set of error signals indicating deviations
in the rate of movement of the moving mirror from the
constant rate and a second set of error signals indi-
5 cating deviations in the angular tilt of the moving
mirror from the constant angular tilt. Finally, there
is a servo system which receives the first and second
sets of error signals and provides corresponding
control signals to the drive mechanism to correct for
10 the deviations from the constant rate and from the
constant angular tilt.

In a particular embodiment of the invention, a
uniquely configured step, having a thickness of $\lambda/8$
(λ being the wavelength of the monochromatic source)
15 is located on the fixed mirror, and it introduces a
90-degree phase shift in portions of the light beam
which reflect from the fixed mirror. The recombined
beams are directed onto an optical detector array in
which distinct segments of the array receive light from
20 corresponding points on the fixed mirror, including the
 $\lambda/8$ -thick step. Electronic circuitry associated with
the system derives both velocity and tilt data by de-
termining the fringe frequency of the detected light
signals, and by analyzing the phase differences between
25 the signals sensed by various combinations of detectors
within the array.

Tilt and velocity error signals are generated and
supplied via a servo system to a drive coil arrangement
which suitably adjusts the moving mirror.

30 The moving mirror is supported on a flexible
diaphragm which prevents the mirror from rotating about
an axis perpendicular to its reflecting surface or from
translating laterally, i.e., perpendicularly to its



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I intended direction of motion. The control system maintains velocity and position of the mirror along the axis of intended motion and corrects for angular tilts outside of the plane normal to that axis.

5 DESCRIPTION OF THE DRAWINGS

FIG. 1 is a schematic representation of an interferometer incorporating an embodiment of the present invention;

FIG. 2 is a detail view, partially in section, of
10 the diaphragm and drive coil transport mechanism used for scanning the moving mirror;

FIG. 3 is a detail view, taken along the line 3-3 of FIG. 2, of the mirror support diaphragm;

FIG. 4 is a detail view of the $\lambda/8$ -thick step on
15 the interferometer fixed mirror;

FIG. 5 is a diagram of a mirror coordinate system for defining the deviation coordinates resulting from an arbitrary tilt of the moving mirror;

FIG. 6 is a diagram showing the geometry of the
20 voice coils of FIG. 2 relative to the X and Y axes;

FIG. 7 is a schematic diagram of the control circuitry associated with the embodiment of FIG. 1;

FIG. 8 is a detail schematic of the DECODER block of FIG. 7;

25 FIG. 9 is a detail schematic of the VELOCITY CIRCUIT block of FIG. 7;

FIG. 10 is a detail schematic of the Z-SERVO CIRCUIT BLOCK of FIG. 7;

FIG. 11 is a detail schematic of the X and Y-SERVO
30 CIRCUIT block of FIG. 7;

FIG. 12 is a detail schematic of the MATRIX CIRCUIT block of FIG. 7;

FIG. 13 is a detail view of an alternate configura-



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i tion of the $\lambda/8$ -thick step of FIG. 4; and

FIG. 14 is a curve showing the force vs stroke characteristic of the diaphragm of FIG. 3.

DESCRIPTION OF THE PREFERRED EMBODIMENT

5 The illustrated embodiment of the present invention is described as being incorporated within a continuous-scanning Michelson Interferometer, forming a part of a Fourier Transform Infrared (FTIR) Spectrometer. However, it should not be interpreted that its use is re-
10 stricted to such an application.

As shown in FIG. 1, a beam of light 11 from a monochromatic source 13, for example a helium-neon (He-Ne) laser, is collimated by an input optical element 15. The beam is incident on a beamsplitter/
15 compensator combination 17 which divides the beam into two component beams 11a, 11b, traveling along two separate optical paths, a first path leading to a fixed mirror 19, and a second path leading to a moving mirror 21. Each of the component beams is incident on its
20 respective mirror normal to its reflective surface. The moving mirror is connected to a support and drive mechanism indicated generally by reference numeral 23 which effects movement of the mirror, including a scanning motion over a limited range in a direction
25 parallel to the direction of the incident beam 11a.

The unique support and drive mechanism 23, in conjunction with the continuous control exercised by a closed-loop servo system to be described hereinafter, provides automatic stable alignment of the moving
30 mirror 21 with respect to the fixed mirror 19 as the moving mirror is scanned. Such control is needed because of the absence of a precise rigid mechanical structure for restricting the motion of the moving



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1 mirror to a predetermined path, as is found in most
prior art interferometers. This combination also makes
instantaneous adjustments to compensate for vibration-
induced deviations from the desired tilt and velocity
5 of the moving mirror.

Referring now to FIG. 2, the moving mirror 21 is
seated within a central aperture 25 of a thin corruga-
ted metal diaphragm 27, and is firmly secured to the
diaphragm by suitable means. The diaphragm, whose
10 surface is contoured by a concentric series of circum-
ferential convolutions 28, is clamped tightly to inter-
ferometer chassis 29. The diaphragm allows the mirror
to be both driven in the desired scanning direction and
tilted with minimal resistance. In effect, the mirror
15 floats on the diaphragm suspension. However, the
diaphragm also must provide sufficient resistance to
undesired rotation and lateral movement of the mirror.
To achieve these conflicting goals, the diaphragm has
six radial apertures 30 (see FIG. 13) evenly spaced
20 about its surface. These apertures enhance the dia-
phragm's flexibility, or compliance, in the axial
direction by a factor of about 20, while retaining
adequate lateral stiffness. Additionally the outermost
convolution 28a is partially flattened after conven-
25 tional "hardening" of the diaphragm, so as to place
all of the convolutions 28 in radial compression. This
achieves the advantage of a diaphragm spring rate that
can be controlled from slightly positive to slightly
negative over the usual working range of deflections,
30 as shown in the curve of FIG. 14.

The rear surface 21a of the moving mirror 21 pro-
trudes through the central aperture of the diaphragm
27, and coupled to this rear surface are three drive

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1 coil assemblies 31. Each assembly includes a cylindrical housing 33 firmly attached to the rear surface of the mirror itself, and several turns of electrically conductive wire 35 wrapped about the outer surface of
5 the housing. Each housing accommodates one of three magnetic pole pieces 37 which are extensions of a powerful ceramic magnet assembly 39. The pole pieces fit loosely enough within their respective housings to permit easy longitudinal repositioning within the
10 housing. When current passes through any winding, the electromagnetic field thus induced interacts with the magnetic field of the pole piece and exerts a longitudinal force thereon. The direction and magnitude of the force depend on the polarity and the magnitude,
15 respectively, of the current. The force acts to move the housing along the fixed pole piece, in turn maneuvering the mirror about its diaphragm suspension.

In the absence of any perturbing vibrational effects on the moving mirror 21, a basic drive signal
20 is supplied simultaneously to the three coils, to scan the mirror between a first set of mechanical stops 38, which define its at rest position, and a second set of stops 40. Typically this is a distance of 0.5 centimeters. When the mirror is set against the first set
25 of stops 38, the moving mirror is aligned so that its reflective surface is perpendicular to the incoming light beam 11a (see FIG. 1). Thus at the start of each scan the movement of the mirror is in a direction perpendicular to its reflective surface. However, in the
30 presence of vibration, different compensating signals must be supplied to each coil, superimposed on the basic drive signal, to maintain the mirror in an untilted orientation, i.e., perpendicular to the incoming



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1 beam, as well as to maintain a uniform scanning velocity. The generation of these compensating signals will be described in greater detail hereinafter.

Referring again to FIG. 1, the beam component 11b
5 traveling along the first path illuminates a portion of the planar reflecting surface 41 of the fixed mirror 19, which includes a raised cross-shaped step 43 protruding above the surface. The cross-shaped step also is reflective and has a thickness of $\lambda/8$, λ being the
10 wavelength of the He-Ne laser beam ($\lambda=0.6328\mu\text{m}$ being a typical wavelength). It should be noted that this monochromatic beam can be transmitted simultaneously with a polychromatic infrared beam which irradiates the sample being analyzed. However, only the monochromatic
15 beam is incident on that portion of the fixed mirror having the step 43.

As shown in FIG. 4, the illuminated portion of the fixed mirror 19 can be divided into nine distinct areas, labeled from A to I. Clearly, light impinging
20 on and reflecting from areas B, D, F and H within the cross-shaped section will travel a distance of $\lambda/4$ less than the light incident on areas A, C, G, and I, and so will undergo a phase shift of 90° with respect thereto. Area E has its reflective surface obliterated, and so reflects no light whatsoever, for reasons
25 to be discussed hereinafter. Alternatively the cross-shaped section can be recessed by a distance $\lambda/8$ within the fixed mirror planar surface 41, to effect the same 90° phase shift.

30 Upon reflection from the respective mirrors, the component beams again pass through the beam splitter/compensator combination 17, are recombined, and are focused by an output optical element 45 onto a detector



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1 array 47. The detector array consists of a three-by-
 three square matrix of nine silicon photodetectors 49,
 each positioned so as to receive light reflected from
 a corresponding area of the fixed mirror 19, and each
 5 generating an electrical output signal proportional to
 the intensity of the light incident thereon. Detector
 A receives light from area A of the fixed mirror,
 detector B receives light from area B, and so on.
 Since the reflective surface of area E on the fixed
 10 mirror was obliterated, detector E receives only light
 from the moving mirror 21. Thus, detector E serves to
 monitor the variations in intensity of the laser source
 13.

For the interferometer to render accurate measure-
 15 ments, the moving mirror 21 must be scanned at a con-
 stant velocity, with its reflective surface maintained
 normal to the beam incident thereon. If these condi-
 tions are met, then, when the two reflected beams are
 recombined and focused onto the detector array 47, the
 20 optical retardation occurring at detectors B, D, F and
 H will be exactly 90° out of phase with the optical
 retardation at detectors A, C, G and I, due to the
 influence of the cross-shaped step 43. In general, the
 output signals generated by the non-phase-shifted
 25 detectors can be represented by a cosine function,
 whereas those generated by the phase-shifted detectors
 can be represented by a sine function (i.e., signals
 in quadrature) as follows:

$$I_1 = I_1^0 \cos 2\pi\sigma\zeta \quad (\text{for detectors A, C, G, I})$$

$$30 \quad I_1 = I_2^0 \sin 2\pi\sigma\zeta \quad (\text{for detectors B, D, F, H})$$

where σ = the optical frequency of the laser source in
 cm^{-1} and ζ is the optical retardation, which changes
 over time as the moving mirror is scanned. However,



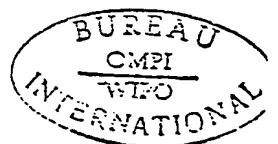
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1 if, because of vibration from the outside environment,
the moving mirror 21 is randomly tilted from its de-
sired position, then the optical retardation at certain
detectors will contain an additional phase component
5 indicative of the amount of tilt.

Referring now to FIG. 5, the effect of an arbitrary
tilt of the moving mirror 21 from its static alignment
position relative to the fixed mirror 19 can be seen.
Here, the fixed mirror 19 is taken to be normal to the
10 Z-axis, with its surface lying in the X, Y plane (i.e.,
Z=0). The fixed mirror is oriented such that the
center area E of the cross-shaped step 43 is located
at the origin of the coordinate axes, with areas D and
F directly on the X-axis at locations (-L, 0) and (+L,
15 0) respectively, and areas B and H on the Y-axis at
locations (0, +L) and (0, -L) respectively. The moving
mirror is tipped by an angle θ from the Z-axis with the
axis of rotation denoted by R_{XY} . R_{XY} is at an
angle ϕ relative to the X-axis. The normal to the
20 tilted moving mirror surface is labeled \hat{n} . A point in
the tilted plane, $P_f = (X_f, Y_f, Z_f)$, may be
related through the angles (θ, ϕ) to a point in the
untilted (X,Y) plane $P_o = (X_o, Y_o)$. The exact re-
lationship between points P_f and P_o is expressed
25 as:

$$\begin{bmatrix} X_f \\ Y_f \\ Z_f \end{bmatrix} = \begin{bmatrix} \cos^2 \phi + \sin^2 \phi \cos \theta & \sin \phi \cos \phi (1 - \cos \theta) \\ \sin \phi \cos \phi (1 - \cos \theta) & \sin^2 \phi + \cos^2 \phi \cos \theta \\ \sin \theta \sin \phi & -\sin \theta \cos \phi \end{bmatrix} \begin{bmatrix} X_o \\ Y_o \end{bmatrix}$$

30 For the expected range of tilt angles (-10° sec),
 $\cos \theta = 1$ and $\sin \theta = \theta$, and so the expression can be
simplified to:



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$$\begin{bmatrix} X_f \\ Y_f \\ Z_f \end{bmatrix} = \begin{bmatrix} 1 & & 0 \\ 0 & & 1 \\ \theta \sin \phi & & -\theta \cos \phi \end{bmatrix} \begin{bmatrix} X_o \\ Y_o \\ Z_o \end{bmatrix}$$

Table 1 gives the untilted coordinates (X_o , Y_o) and the tilted, or deviation, coordinates (X_f , Y_f , Z_f) corresponding to each of the detector positions shown in FIG. 4. It can readily be seen that due to the approximations made, the amount of tilt is reflected by a change in the Z-direction coordinate.

10

TABLE I

DETECTOR	X_o	Y_o	X_f	Y_f	$Z_f(\theta, \phi) = \frac{z_f(\theta, \phi)}{2}$	$Z_f(\alpha, \beta) = \frac{z_f(\alpha, \beta)}{2}$
A	-L	L	-L	L	$-\theta L(\sin \phi + \cos \phi)$	$-L(\alpha + \beta)$
B	0	L	0	L	$-\theta L(\cos \phi)$	$-L(\beta)$
C	L	L	L	L	$\theta L(\sin \phi - \cos \phi)$	$L(\alpha - \beta)$
D	-L	0	-L	0	$-\theta L(\sin \phi)$	$-L(\alpha)$
E	0	0	0	0	0	0
F	L	0	L	0	$\theta L(\sin \phi)$	$L(\alpha)$
G	-L	-L	-L	-L	$-\theta L(\sin \phi - \cos \phi)$	$-L(\alpha - \beta)$
H	0	-L	0	-L	$\theta L(\cos \phi)$	$L(\beta)$
I	L	-L	L	-L	$\theta L(\sin \phi + \cos \phi)$	$L(\alpha + \beta)$

The deviation in the Z-direction of the physical position of the moving mirror 21 can be equated to the change in the optical retardation of the light beam reflected from that mirror. If the mirror, in its untilted mode, is assumed to be moving at a velocity v in the Z-direction, then the optical retardation ζ over time t can be represented by $\zeta = 2vt$ (the factor "2" is due to the fact that the beam twice traverses the change in mirror position, i.e., in impinging on, and being reflected from, the mirror). Thus, in the tilted case, the optical retardation at each detector position

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1 is the algebraic sum of ζ plus ζ_f , where $\zeta_f = 2Z_f$.

If α is defined as $\alpha = \theta \sin \phi$ and β as $\beta = \theta \cos \phi$, then the resulting output signal I_n (in arbitrary units) from the n th detector can be represented as:

$$I_n(\zeta, \alpha, \beta) = I_n^m + I_n^f + 2\sqrt{I_n^m I_n^f} \cos(\theta_o + \theta_n(\alpha, \beta))$$

for $n=A, C, G, I$

Eq. (1)

$$I_n(\zeta, \alpha, \beta) = I_n^m + I_n^f + 2\sqrt{I_n^m I_n^f} \sin(\theta_o + \theta_n(\alpha, \beta))$$

for $n=B, D, F, H$

Eq. (2)

where $\theta_o = 2\pi\sigma\zeta$

$\phi_n = (2\pi\sigma\zeta_f)_n$ (see Table I)

σ = optical frequency of the laser source

and

I_n^m, I_n^f are the signals reflected from corresponding portions of the moving and fixed mirrors, respectively.

Clearly, Eqs. (1) and (2) are analogous to the quadrature signals discussed earlier with regard to the untilted case, except that the argument of the sine and cosine terms differ (e.g., $\theta_A(\alpha, \beta) \neq \theta_B(\alpha, \beta)$), the difference being related to the magnitude of the tilt.

It should be pointed out that Eqs. (1) and (2) are based on the assumption that the thickness of the $\lambda/8$ -thick step is uniform. If this is not the case, then an additional phase term ψ can be entered into the argument of the sine and cosine terms to compensate for the lack of uniformity.



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1 Referring now to FIG. 7, each of the nine output signals I_n , usually in the form of d.c. current signals proportional to the intensity of the incident light, is fed to a corresponding pre-amplifier 51. The
 5 gain of each pre-amp is slightly different, because of the non-uniformity of the detectors. This yields a series of normalized signals I_n' each having the same minimum and maximum values. Only I_E' , the reference signal, is adjusted for a different value,
 10 equal to the average value of the I_n' signals.

The amplified signals I_n' are entered into a decoder circuit 53 which, as shown in detail in FIG. 8, comprises an assembly of conventional additive and
 15 multiplicative components, well known to those skilled in the electronics arts. These components are configured so as to combine the signals I_n' according to the following formulas, to yield error signals e_x and e_y :

$$20 \quad e_x = \left(\frac{I_A' + I_G'}{2} - KI_E' \right) (I_F' - KI_E') - \left(\frac{I_C' + I_I'}{2} - KI_E' \right) (I_D' - KI_E')$$

$$e_y = \left(\frac{I_A' + I_C'}{2} - KI_E' \right) (I_H' - KI_E') - \left(\frac{I_G' + I_I'}{2} - KI_E' \right) (I_B' - KI_E')$$

e_x and e_y represent the amount of tilt of the
 25 moving mirror from its desired orientation in the X-and Y-directions, respectively. The constant factor K adjusts for variations in the intensity of the He-Ne laser, to maintain the input into the decoder circuit 53 from the detector E at a constant level. In this
 30 manner, the average value of each quantity within parentheses is 0, because of the appropriate selection of the average values of the I_n' signals and I_E' , as discussed above. This adjustment prevents the

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1 generation of undesirable harmonics in the error signals, which would cause instability in the servo loop. Using Eqs. (1) and (2) and the values of $\zeta_f(\alpha, \beta)$ in Table I, the expressions for e_x and e_y can be
 5 reduced to:

$$e_x = \sin(8\pi\sigma L\alpha) \cos(4\pi\sigma L\beta)$$

$$e_y = \sin(8\pi\sigma L\beta) \cos(4\pi\sigma L\alpha)$$

To generate the Z-position and the Z-velocity error signals, to correct for vibration-induced fluctuations in the desired mirror scanning velocity v of the moving mirror 21 (which is assumed to be along the Z axis), two additional quadrature signals V_1 , V_2 are considered.

V_1 is the average value of the output signals I_n' from the four cosine detectors (i.e., $n=A, C, G, I$), while V_2 is the average value of the signals I_n' from the four sine detectors (i.e., $n=B, D, F, H$). As can be readily seen in FIG. 8, the two values V_1 , V_2 are achieved within the decoder circuit 53, with the resultant signals V_1 and V_2 appearing on output lines 57, 58 respectively.

Referring again to FIG. 7, the Z-position error signal is developed by multiplying the cosine term V_1 , within a phase detector circuit 59, by a signal from a constant frequency clock 60. The phase detector circuit can be any one of a variety of conventional circuits of this type, as known to those skilled in the electronics arts. The temporal frequency f_r of the clock signal corresponds to the frequency σ of the He-Ne visible light source, i.e., $f_r = 2v\sigma$. The value of f_r used in the illustrated embodiment is 1634 Hz. It should be noted that f_r is actually the frequency of the interference fringes developed from the visible



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1 light source 13 by the moving mirror 21, if it is moving at the desired velocity v . By passing the product of these two signals through a filter (not shown) that does not pass frequencies greater than f_r , then only
 5 a signal having a difference frequency $\Delta f = f_z - f_r$ remains, where $f_z = 2v_z \sigma$ and v_z is the instantaneous velocity. For small differences in position, the Z-position error signal e_z , appearing at the output of the phase detector circuit, can be expressed as:

$$10 \quad e_z = (\text{constant})(2\pi\Delta f)$$

This signal e_z forms one input to a mirror drive Z-servo circuit 61 to be discussed in greater detail hereinafter.

While the Z-position error signal e_z is being
 15 developed, a Z-velocity measurement signal E_v also is being generated from the V_1 and V_2 quadrature signals. Referring again to FIG. 7, the cosine signal V_1 and the sine signal V_2 are introduced into a velocity circuit 63. As shown in more detail in
 20 FIG. 9, the V_1 signal is processed through a differentiator 65, and the differentiated signal V_1' is multiplied by the V_2 signal within a multiplier 67. Similarly, the V_2 signal is fed through a differentiator 69 and the resulting V_2' is multiplied by the
 25 V_1 signal within a multiplier 71. The respective outputs of the multipliers are then subtracted by the operation of an operational amplifier 73 to yield the quantity

$$E_v = V_1 V_2' - V_1' V_2$$

30 which can be shown to be reducible to the basic form

$$E_v = (\text{constant}) v$$

i.e., linearly dependent on the instantaneous mirror velocity v . E_v forms a second input into the mirror



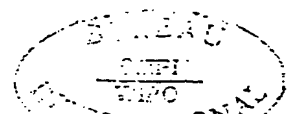
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1 drive Z-servo circuit 61 (see FIG. 7).

In addition to the e_z and E_v signals, the mirror drive Z-servo circuit 61 receives via line 74 (see also FIG. 10) a constant input voltage signal K_v which corresponds to the desired mirror velocity v . Thus, the Z-servo circuit, shown in detail in FIG. 10, which also is a conventional circuit well known to those skilled in the electronics art, is able to derive from these inputs a velocity error signal $e_v = E_v - K_v$. Subsequently, the Z-servo circuit generates a signal e_z total on line 75, which incorporates both the Z-position error signal e_z and the Z-velocity error signal e_v .

The Z-servo circuit 61 also performs frequency compensation on the e_z TOTAL signal, so that the appropriate phase criteria are met to ensure stability of the servo loop. Finally, the circuit feeds a voltage signal V_z , containing the combined Z-position and Z-velocity error information, along a line 76 to a matrix circuit 77. Similarly, an X and Y-servo circuit 79, shown in greater detail in FIG. 11, processes and frequency compensates the e_x and e_y signals to yield voltage signals V_x and V_y respectively, and in turn supplies these voltage signals to the matrix circuit.

Referring again to FIG. 7, the matrix circuit 77 (see also FIG. 12), in combination with four power amplifiers 81, reconfigures and scales the three signals V_x , V_y and V_z into a form which achieves the desired reorientation of the moving mirror 21, given the particular arrangement of the drive coils 31. The scaling operation ensures that a signal of a given magnitude produces the same amount of torque whether



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1 applied in the X-direction or the Y-direction. Refer-
ring now to FIG. 6, the three coils, identified as
coils I, II and III, are spaced in a circular pattern,
at 120° intervals. Assuming that the mirror in its
5 untilted orientation is lying entirely in the X-Y
plane, coil I is located directly on the X-axis, and
coils II and III are at 60° on either side of that
axis. Four voltage signals are applied to the drive
coils via the four preamplifiers 81, to produce an ac-
10 tuating current within each coil. The first signal,
 V_Z , is supplied commonly to all three coils via a
line 83, to effect the basic scanning motion of the
mirror at the appropriate velocity. In addition, the
following three signals also are supplied individually
15 to coils I, II, and III, superimposed on V_Z , to apply
the necessary tilt corrections:

$$\text{I:} \quad -V_X$$

$$\text{II:} \quad \frac{V_X}{2} + V_Y$$

$$\text{III:} \quad \frac{V_X}{2} - V_Y$$

It should be noted that both servo circuits 61 and
77 (see FIG. 7) also receive input signals from a con-
25 troller 78. The controller, which can be a micropro-
cessor or any of a variety of similarly functioning
devices, coordinates the overall operation of the drive
system. For example, the controller initiates the
motion of the moving mirror 21 to start a scanning
30 cycle. At the start of a scan, the controller causes
the moving mirror to be pulled back against the mech-
anical stops 38 in order to give a rough alignment, so
that the drive system can achieve an initial lock.

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1 Also, since the drive system has a limited dynamic range, on the order of a few arc seconds of tilt, any tilt beyond this range causes the servo circuits 61, 77 to lose lock. In this situation the controller
5 receives from the Z-servo circuit 61 a "Z ERROR INTERRUPT" signal (see FIG. 10), and in turn returns the moving mirror to its reference point against the mechanical stop, before initiating a new scan. Also, the controller is used to keep track of where the mirror
10 is in relation to its overall range of movement, to permit scanning in the reverse direction once the end point has been reached. However, the functioning of this controller is peripheral to the novel aspects of the present invention, and as such will not be dealt
15 with in any further detail herein.

It should be mentioned that alternate configurations of the $\lambda/8$ -thick step 43 and to the photodetector array 47, are usable in the present invention, an example of which is shown in FIG. 13. Here a step 43'
20 encompasses three areas labeled S, while the adjacent surface of the fixed mirror 19 encompasses five distinct areas labeled C. Light reflecting from the three areas S is phase-shifted by 90° relative to that reflected from the areas C, accounting for the sine and
25 cosine signals respectively. Clearly the use of this alternate configuration requires a corresponding modification to the mathematical equations describing the signals generated thereby.

The interferometer drive system in accordance with
30 the present invention offers several advantages over prior art systems. In many prior art systems velocity and position fluctuations were detected by observing changes in the times of the zero crossings of the



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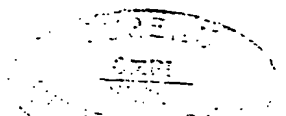
1 interference fringes. However this technique puts an
upper limit on the frequency at which updated informa-
tion is provided to the mirror drive servo. In other
words, the servo is unable to correct for vibrations
5 above a certain frequency. For example, assume that
the moving mirror is to be scanned so as to produce
1630 fringes per second. Since data sampling at the
fringe zero crossings means that only two samplings
occur per cycle, then, according to the Nyquist cri-
10 terion, the servo system cannot respond to a signal
having a frequency greater than 1630Hz. Accordingly,
the effective servo bandwidth would be only one-third
to one-half of the 1630Hz, severely limiting its vibra-
tion-compensating ability. With the present invention,
15 however, essentially continuous sampling of the X and
Y positional data and Z-velocity data is available,
thereby achieving greater servo bandwidth which allows
the drive system to respond to higher frequency per-
turbations.

20 The provision of continuous data allows the use of
a relatively simple mechanical suspension for the
moving mirror. Mechanical complexity is replaced by
electronic circuitry, which provides greater accuracy
and reliability at a lower cost. Also, the large
25 number of photodetectors 49 and the nature of the phase
difference signals generated thereby are instrumental
in ensuring that the moving mirror 21 remains under
servo control even when the mirror is stationary, and
at the time of scan reversal.

30 Although the present invention has been described
in terms of a preferred embodiment, as shown in the
accompanying figures, certain modifications and changes
may become apparent to those skilled in the art. For

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- 1 example, the phase-shift producing step can be located
- on the moving mirror 21 instead of the fixed mirror 19,
and can be configured in many different ways, with
corresponding changes in the photodetector array 47.
5 Certain advantages may be achieved by locating the step
not at the center of the mirror, but offset therefrom.
Also, the thickness of the step can be other than $\lambda/8$,
in which case the phase-shifted and non-phase shifted
signals would stand in a non-quadrature relationship.
10 Nevertheless, it is intended that such modifications
be encompassed within the scope of the following ap-
pended claims.



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1 WHAT IS CLAIMED IS:

1. In an interferometer in which a first light beam derived from a monochromatic source is incident on a fixed mirror and a second light beam derived from
5 the same monochromatic source is incident on a moving mirror, wherein said moving mirror is to be moved both at a constant rate and at a constant angular tilt relative to the direction of incidence of said second beam on its reflective surface, and wherein said first and
10 second light beams are recombined after reflection from their respective mirrors, an improved mirror drive control system, comprising:

drive means for both moving said moving mirror and for adjusting the angular tilt thereof;

15 means for deriving from the recombined light beams both a first set of error signals indicating deviations in the rate of movement of said moving mirror from said constant rate and a second set of error signals indicating deviations in the angular tilt of said moving
20 mirror from said constant angular tilt; and

servo means for receiving said first and second sets of error signals and providing corresponding control signals to said drive means to correct for said deviations.

25 2. The mirror drive control system as set forth in claim 1, wherein said drive means moves said moving mirror in a direction so as to maintain its reflective surface perpendicular to said incident second light beam.

30 3. The mirror drive control system as set forth in claim 1, further comprising:

means for introducing a phase shift into a portion of one of said first and second light beams, and where-

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1 in said means for deriving includes means for generating multiphase signals incorporating phase shift data extracted from said recombined light beams, said data being indicative of the rate of movement and the angular tilt of said moving mirror.

4. The mirror drive control system as set forth in claim 3, wherein said phase shift is 90° .

5. The mirror drive control system as set forth in claim 3, wherein said means for introducing a phase shift comprises a reflective element having a thickness which is a predetermined fraction of the wavelength of said monochromatic source, said element being on the reflective surface of one of said mirrors, disposed so that both said element and the adjacent areas of said reflective surface are illuminated by the light beam incident on said one of said mirrors.

6. The mirror drive control system as set forth in claim 4 wherein said means for introducing a 90° phase shift comprises a reflective element having a thickness which is one-eighth the wavelength of said monochromatic source, said element being on the reflective surface of one of said mirrors, disposed so that both said element and the adjacent areas of said reflective surface are illuminated by the light beam incident on said one of said mirrors.

7. The mirror drive control system as set forth in claim 6, wherein said reflective element is located on said fixed mirror.

8. The mirror drive control system as set forth in claim 4, wherein said reflective element is cross-shaped.

9. The mirror drive control system as set forth in claim 1, wherein said drive means comprises:



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1 a flexible diaphragm supporting said moving mirror
for movement thereof; and

a plurality of actuators coupled between said
moving mirror and a fixed location on said interfero-
5 meter for selectively exerting force against said
mirror to effect movement of said mirror about said
diaphragm.

10 10. The mirror drive control system as set forth
in claim 9 wherein said flexible diaphragm includes a
plurality of concentric circumferential convolutions
formed in its surface, the outermost of said convolu-
tions being flattened so as to place the remaining
convolutions in radial compression; and a plurality of
radially extending slits cut into said surface, whereby
15 the compliance of said diaphragm in an axial direction
is enhanced.

11. The mirror drive control system as set forth
in claim 9, wherein each of said actuators comprises:

a magnetic member attached to said fixed location
20 on said interferometer; and

an electrical coil assembly attached to said moving
mirror and loosely surrounding said magnetic member,
and receiving said control signals from said servo
means,

25 whereby the interaction between the magnetic field
of said magnetic member and the magnetic field of each
coil assembly, as induced by the application of said
control signals thereto, effects movement of said coil
assembly relative to said fixed magnetic member.

30 12. The mirror drive control system as set forth
in claim 11, wherein said coil assemblies are arranged
in a circular configuration on said moving mirror at
equiangular spacings.



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1 13. The mirror drive control system as set forth in claim 5, wherein said means for generating multiphase signals comprises:

5 a plurality of optical detectors disposed so that each of a first group of detectors receives light reflected from a corresponding location on said reflective element and each of a second group of detectors receives light reflected from said adjacent areas of said reflective surface.

10 14. In an interferometer of the type in which a first light beam derived from a monochromatic source is incident on a fixed mirror and a second light beam derived from the same monochromatic source is incident on a moving mirror, wherein said moving mirror is to
15 be moved both at a constant rate and at a constant angular tilt relative to the direction of incidence of said second beam on its reflective surface, and wherein said first and second light beams are recombined after reflection from their respective mirrors, the
20 apparatus comprising:

means for deriving from the recombined light beams both a first set of error signals indicating deviations in the rate of movement of said moving mirror from said constant rate and a second set of error signals indicating deviations in the angular tilt of said moving
25 mirror from said constant angular tilt.

15. The apparatus as set forth in claim 14, further comprising:

means for introducing a phase shift into a portion
30 of one of said first and second light beams, and wherein said means for deriving includes means for generating multiphase signals incorporating phase shift data extracted from said recombined light beams, said data



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1 being indicative of the rate of movement and the angular tilt of said moving mirror.

16. The apparatus as set forth in claim 15 wherein said phase shift is 90° .

5 17. In an interferometer of the type in which a first light beam derived from a monochromatic source is incident on a fixed mirror and a second light beam derived from the same monochromatic source is incident on a moving mirror, wherein said moving mirror is to
10 be moved both at a constant rate and at a constant angular tilt relative to the direction of incidence of said second beam on its reflective surface, and wherein said first and second light beams are recombined after reflection from their respective mirrors, the
15 apparatus comprising:

means for introducing a 90° phase shift into a portion of one of said first and second light beams;

means for generating quadrature signals incorporating phase shift data extracted from the recombined
20 light beams, said data being indicative of the rate of movement and the angular tilt of said moving mirror; and

means for deriving from said quadrature signals both a first set of error signals indicating deviations
25 in the rate of movement of said moving mirror from said constant rate and a second set of error signals indicating deviations in the angular tilt of said moving mirror from said constant angular tilt.

18. The apparatus as set forth in claim 17,
30 wherein said means for introducing a 90° phase shift comprises a reflective element having a thickness of one-eighth the wavelength of said monochromatic source, said element being on the reflective surface of said



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1 fixed mirror, disposed so that both said element and the adjacent areas of said reflective surface of said fixed mirror are illuminated by said first light beam.

19. The apparatus as set forth in claim 18,
5 wherein said means for generating quadrature signals comprises:

a plurality of optical detectors disposed so that each of a first group of detectors receives light reflected from a corresponding location on said reflective element and each of a second group of detectors
10 receives light reflected from said adjacent areas of said fixed mirror.



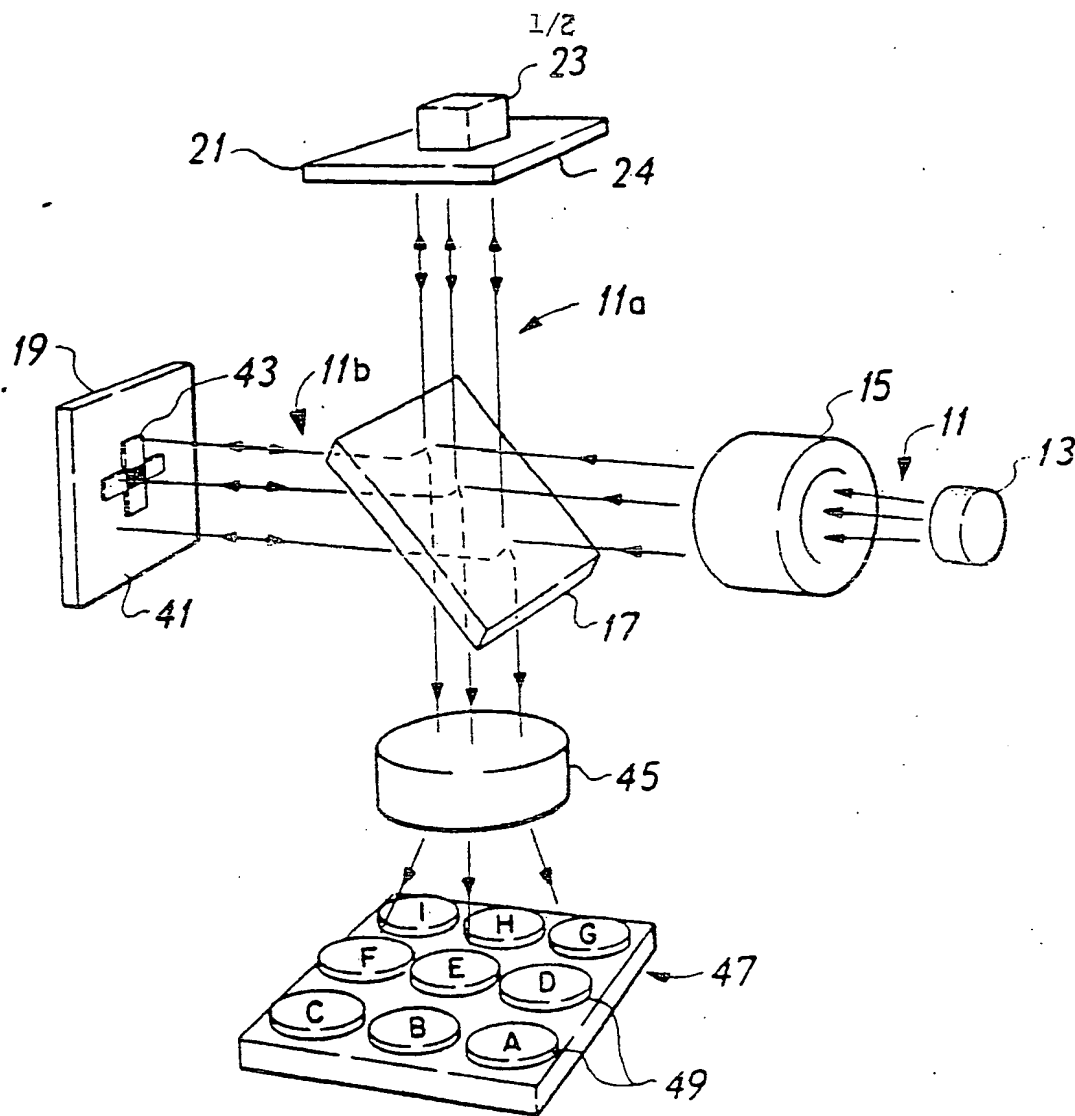


FIG. 1

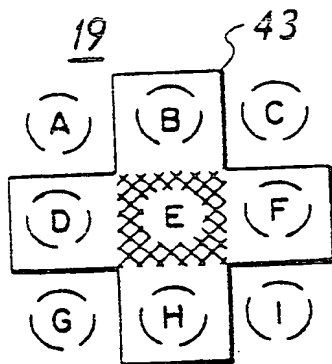


FIG. 4

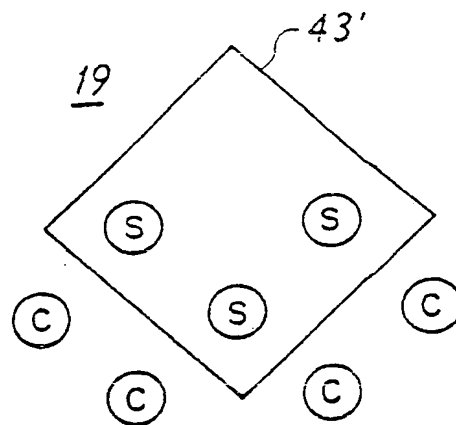


FIG. 13

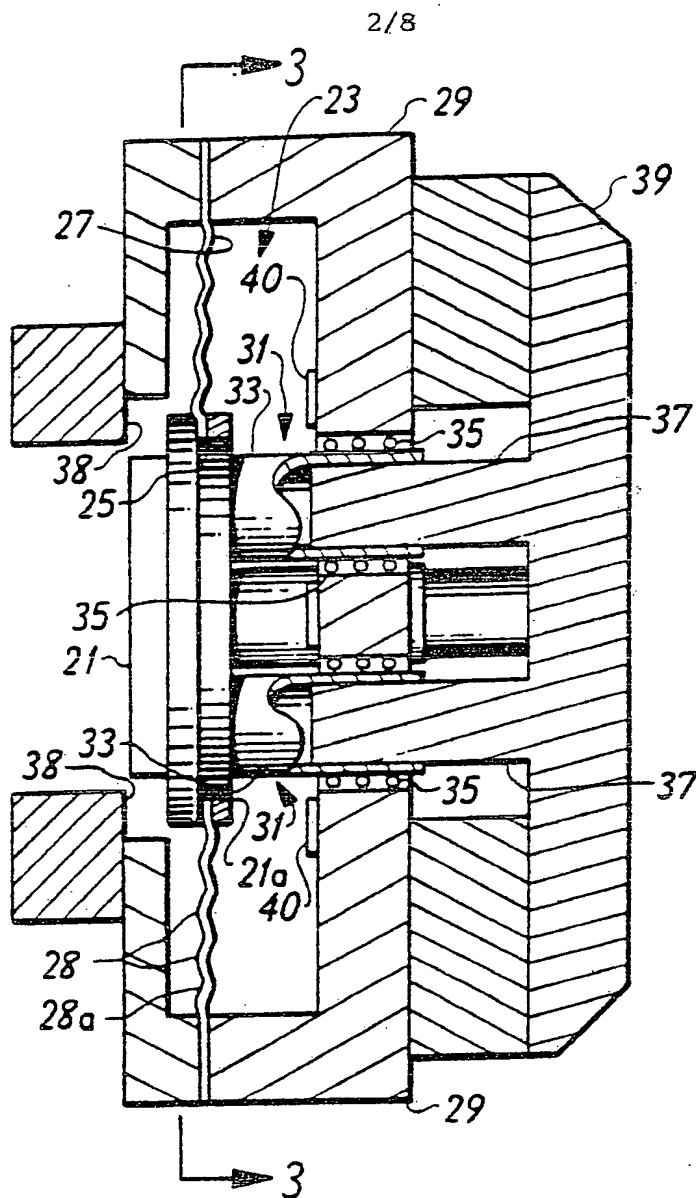


FIG. 2

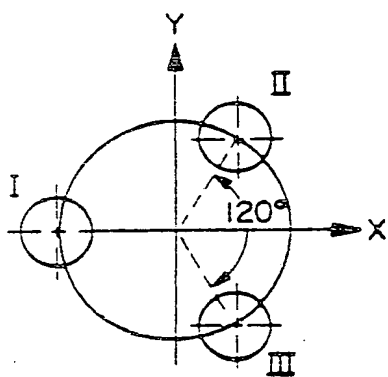


FIG. 6

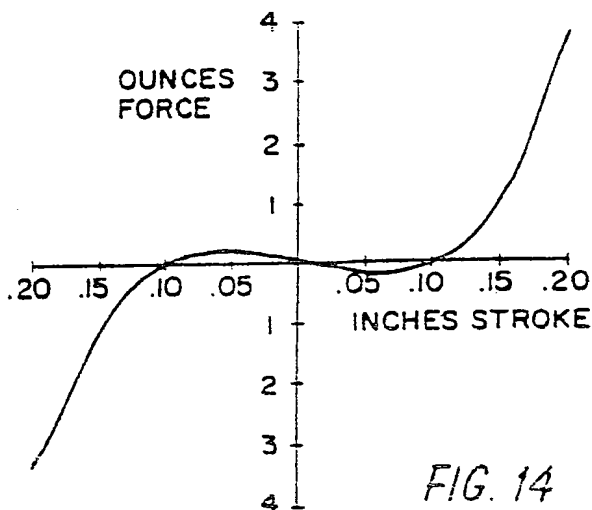


FIG. 14

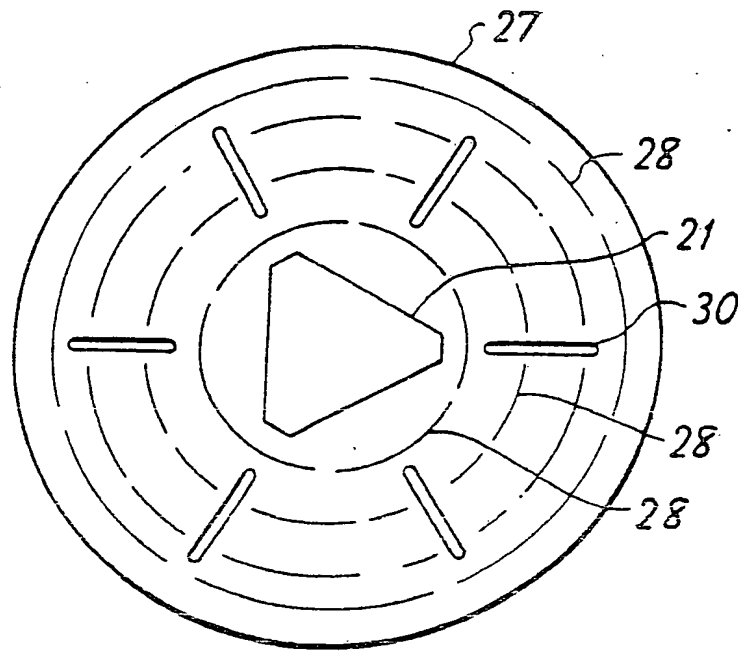


FIG. 3

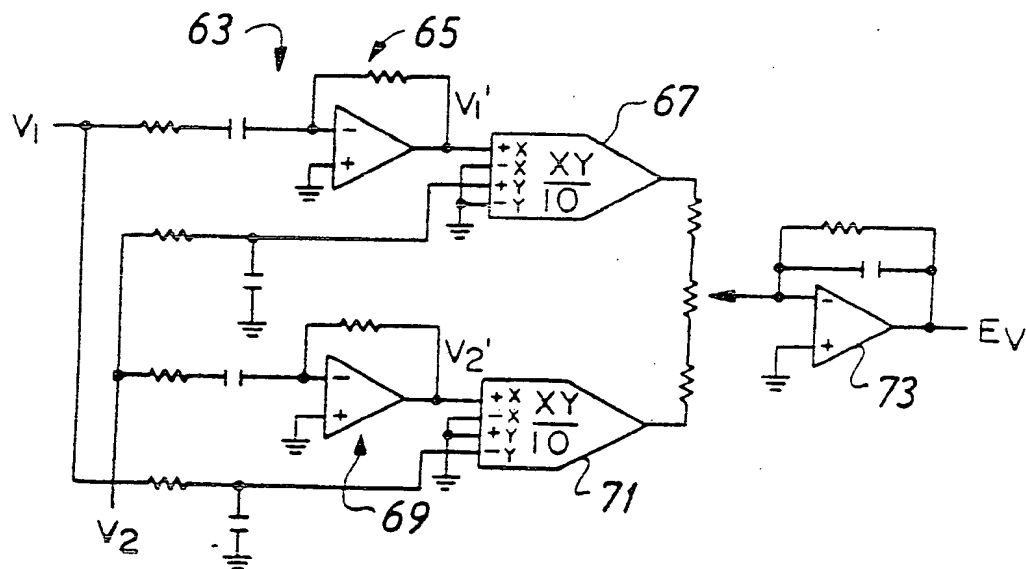
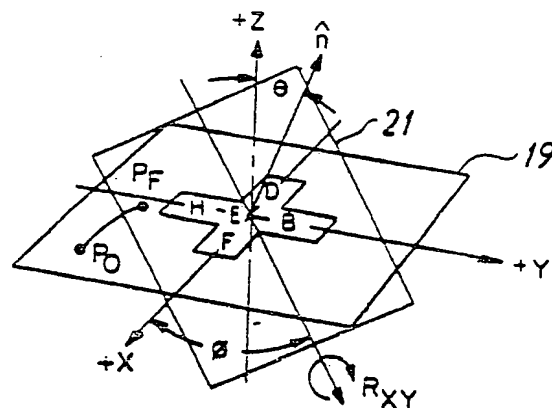
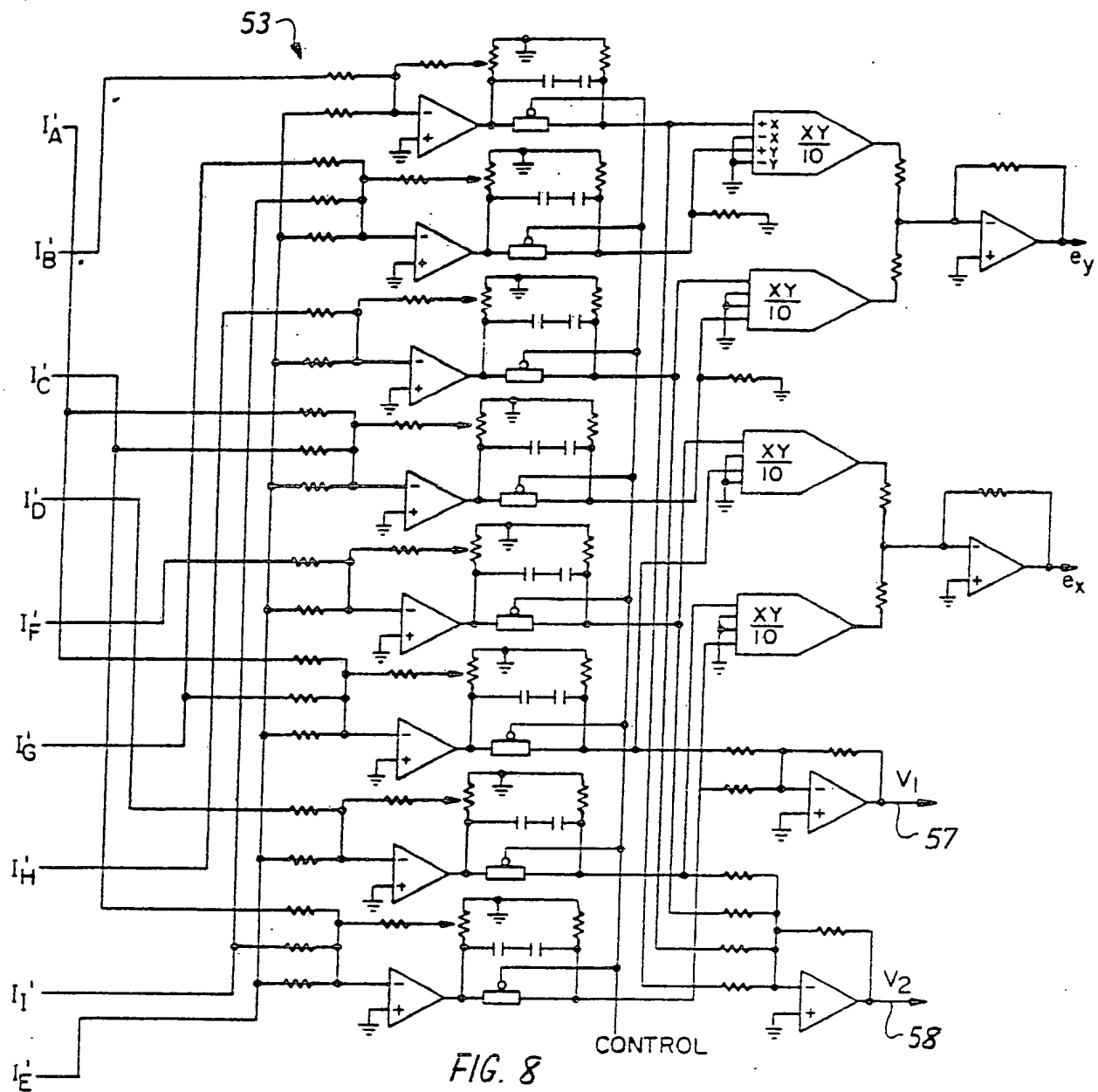


FIG. 9



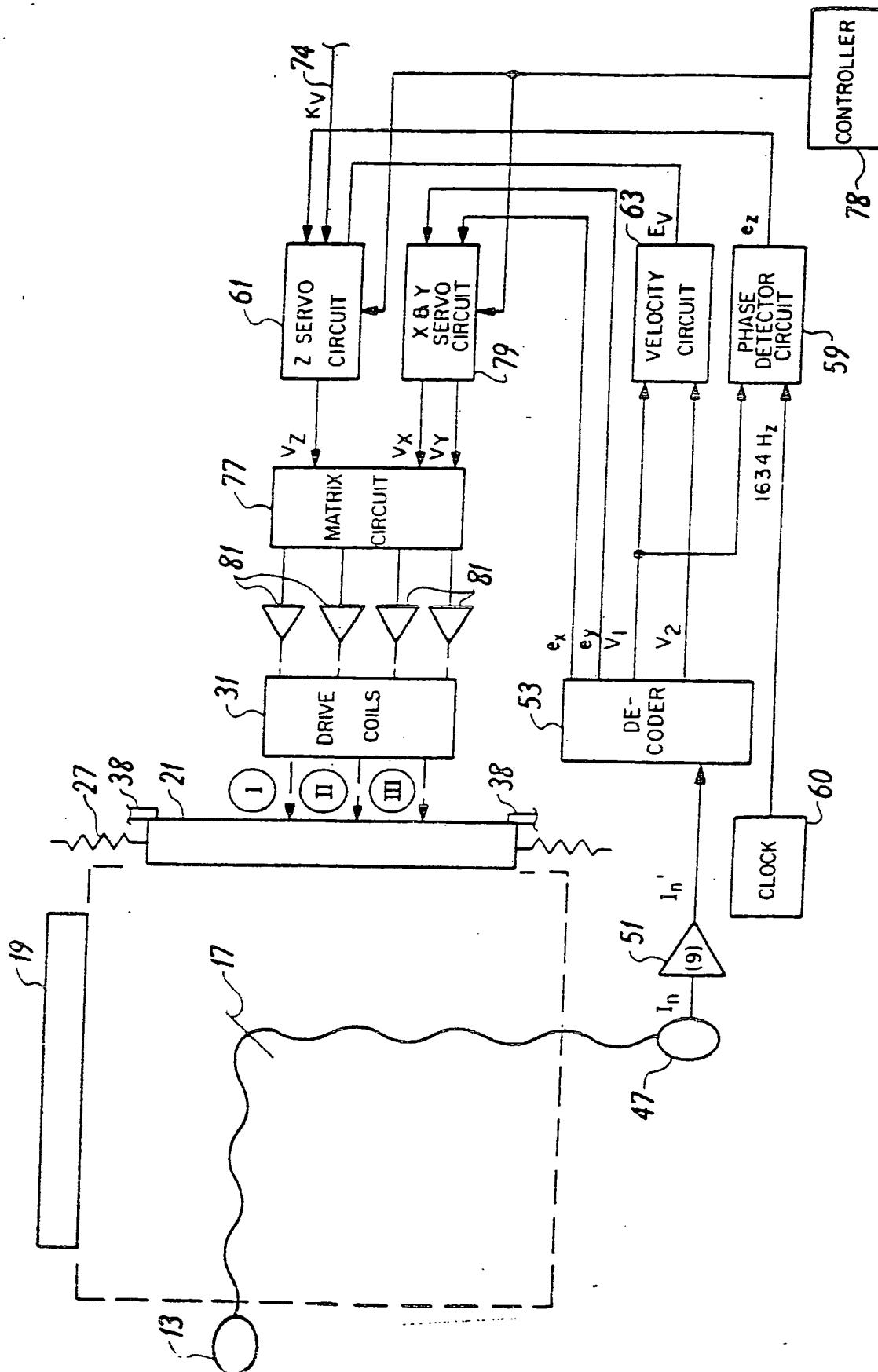


FIG. 7

WQ 84/01211

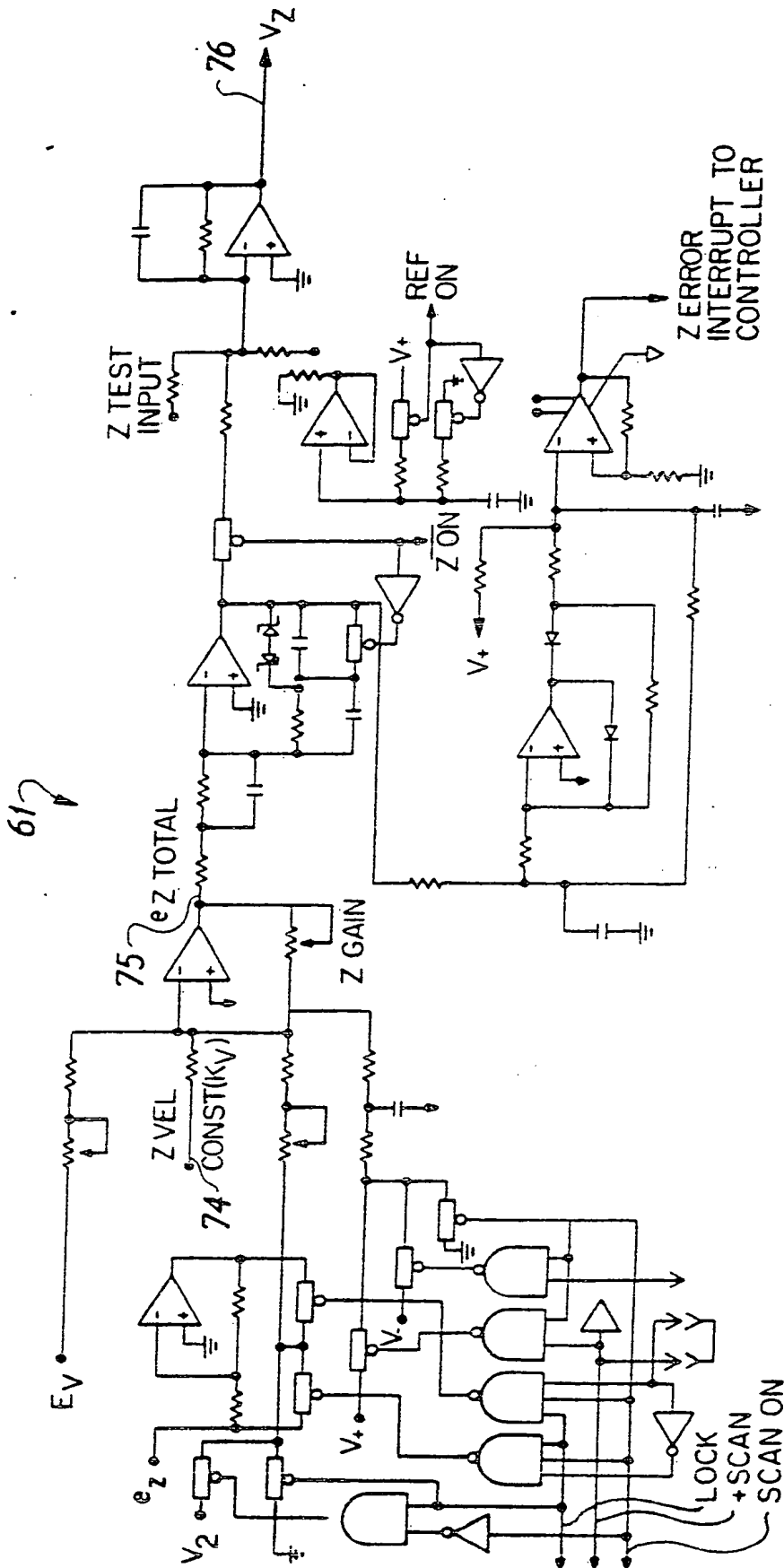


FIG. 10

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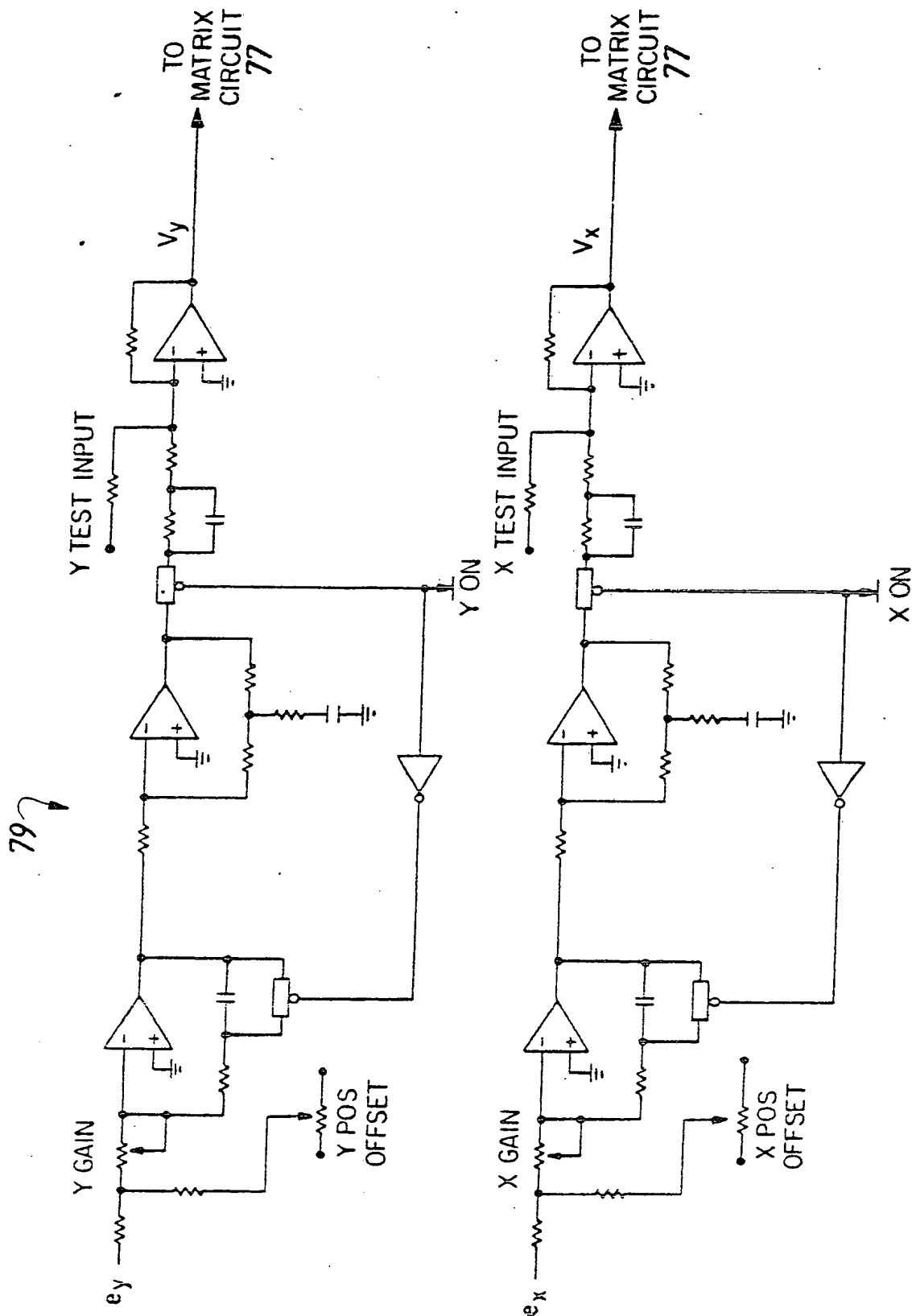


FIG. 11

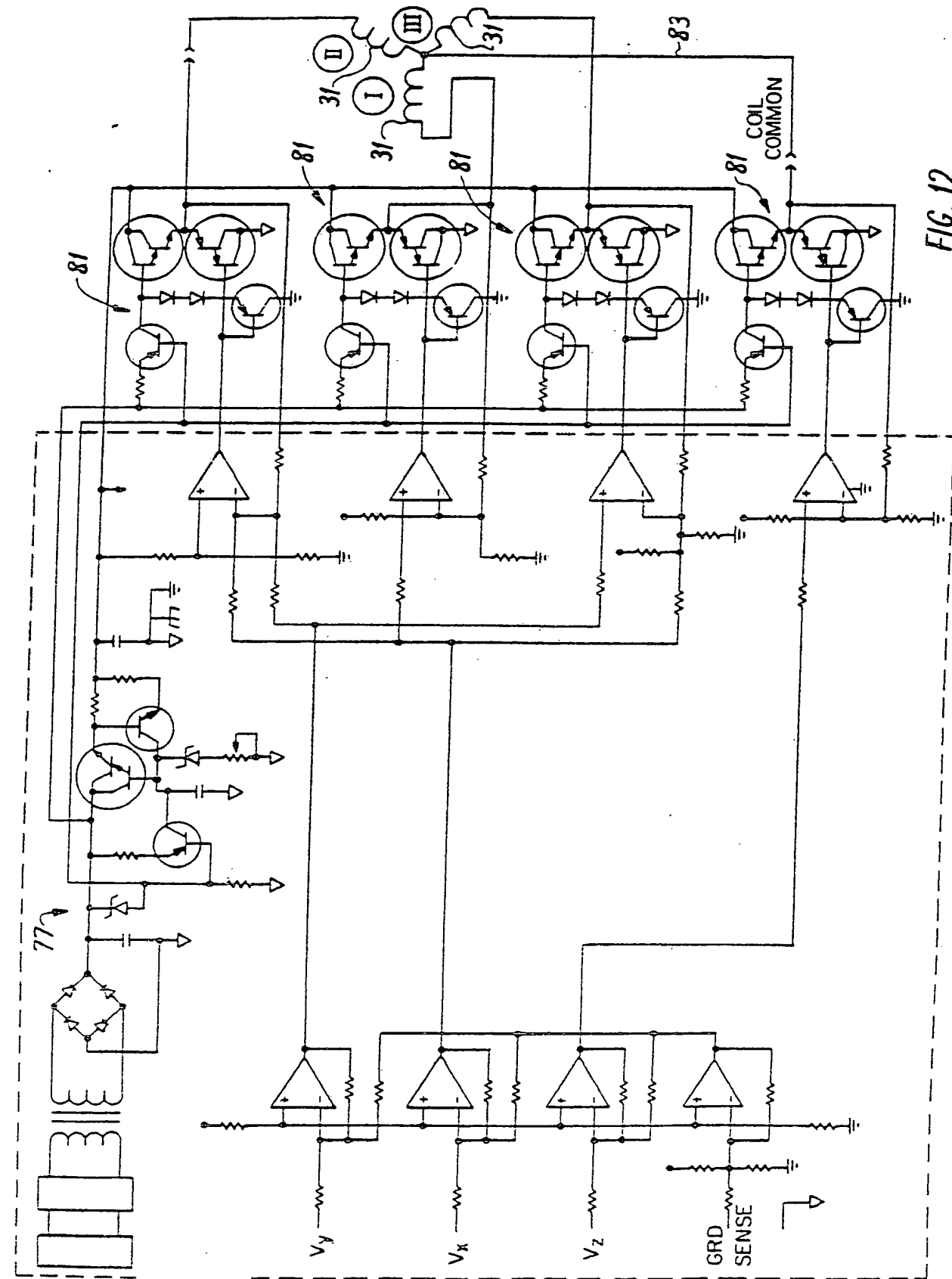


FIG. 12

INTERNATIONAL SEARCH REPORT

International Application No PCT/US 83/01222

I. CLASSIFICATION OF SUBJECT MATTER (If several classification symbols apply, indicate all) *

According to International Patent Classification (IPC) or to both National Classification and IPC

IPC²: G 01 B 9/02

II. FIELDS SEARCHED

Minimum Documentation Searched ⁴

Classification System

Classification Symbols

IPC³

G 01 B 9/02; G 01 J 9/02; G 01 J 3/28; G 02 B 26/08

Documentation Searched other than Minimum Documentation
to the extent that such Documents are included in the Fields Searched ⁵

III. DOCUMENTS CONSIDERED TO BE RELEVANT ¹⁴

Category *	Citation of Document, ¹⁶ with indication, where appropriate, of the relevant passages ¹⁷	Relevant to Claim No. ¹⁸
A	US, A, 4053231 (J. FLETCHER) 11 October 1977 see columns 2-3; figures 1,4 cited in the application --	1
A	Proceedings of the SPIE, vol. 191, "Multiplex and High Through-put Spectroscopy", published in 1979 by SPIE (US) R. Walker et al.: "Interferometer design and data handling in a high vibration environment", part I, pages 88-91, see page 90 cited in the application --	1
A	Optik, vol. 38, no. 3, published in 1973 (Stuttgart, DE) H. Parsche et al.: "Ein laserkontrolliertes Fourier- interferometer für den sichtbaren Spektralbereich", pages 298-310, see pages 302,305 --	1 -./.

* Special categories of cited documents: ¹⁶

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"Y" document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art.

"Z" document member of the same patent family

IV. CERTIFICATION

Date of the Actual Completion of the International Search ¹

1st December 1983

Date of Mailing of this International Search Report ²

04 JAN. 1984

International Searching Authority ¹

EUROPEAN PATENT OFFICE

Signature of Authorized Officer ³⁰

G.L.M. Kruijsenberg

III. DOCUMENTS CONSIDERED TO BE RELEVANT (CONTINUED FROM THE SECOND SHEET)

Category *	Citation of Document, ¹⁶ with indication, where appropriate, of the relevant passages ¹⁷	Relevant to Claim No ¹⁸
A	GB, A, 2042207 (SONY CORPORATION) 17 September 1980 see page 4; figures 7,11 --	9,11
A	DE, A, 2235654 (VICKERS LTD.) 1 February 1973 see pages 3-4; figures 1-2 -----	9-11

ANNEX TO THE INTERNATIONAL SEARCH REPORT ON

INTERNATIONAL APPLICATION NO.

PCT/US 83/01222 (SA 5679)

This Annex lists the patent family members relating to the patent documents cited in the above-mentioned international search report. The members are as contained in the European Patent Office EDP file on 23/12/83

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Patent document cited in search report	Publication date	Patent family member(s)	Publication date
US-A- 4053231	11/10/77	None	
GB-A- 2042207	17/09/80	NL-A- 8000132	11/07/80
		FR-A- 2446523	08/08/80
		DE-A- 3000473	24/07/80
		JP-A- 55093544	16/07/80
		US-A- 4269486	26/05/81
		CA-A- 1134948	02/11/82
DE-A- 2235654	01/02/73	GB-A- 1393896	14/05/75

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